

Priority Application Serial No. 09/141,775
 Priority Filing Date August 27, 1998
 Inventor Guy T. Blalock et al.
 Assignee Micron Technology, Inc.
 Priority Group Art Unit 1765
 Priority Examiner L. Vinh
 Attorney's Docket No. MI22-1544
 Title: Plasma Etching Methods

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. §§1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation of co-pending application Serial No. 09/141,775, filed August 27, 1998. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. §1.98(d) and MPEP §609(2). No admission is made regarding whether all the submitted references are prior art.

Citation of these references is respectfully requested.

Respectfully submitted,
 Dated: Oct 2, 2000
 Attorney: Bernard Berman
 Bernard Berman
 Reg. No. 37,279
 WELLS, ST. JOHN, ROBERTS,
 GREGORY & MATKIN P.S.